

[IEEE HOME](#) | [SEARCH IEEE](#) | [SHOP](#) | [WEB ACCOUNT](#) | [CONTACT IEEE](#)[Membership](#) | [Publications/Services](#) | [Standards](#) | [Conferences](#) | [Careers/Jobs](#)**IEEE Xplore™**  
RELEASE 1.4Welcome  
United States Patent and Trademark Office[Help](#) | [FAQ](#) | [Terms](#) | [IEEE Peer Review](#) | [Quick Links](#)**Welcome to IEEE Xplore™**

- ☐ Home
- ☐ What Can I Access?
- ☐ Log-out

**Tables of Contents**

- ☐ Journals & Magazines
- ☐ Conference Proceedings
- ☐ Standards

**Search**

- ☐ By Author
- ☐ Basic
- ☐ Advanced

**Member Services**

- ☐ Join IEEE
- ☐ Establish IEEE Web Account

 [Print Format](#)Your search matched **1** of **798921** documents.Results are shown **25** to a page, sorted by **publication year** in **descending** order.

You may refine your search by editing the current search expression or entering a new one the te

Then click **Search Again**.**Results:**Journal or Magazine = **JNL** Conference = **CNF** Standard = **STD****1 Spectroscopic Anisotropy Micro-Ellipsometry (SAME) for determinat lateral and vertical dimensions of sub-micron lithographic structures***Michaelis, A.; Gent, O.; Mantz, U.*

VLSI Technology, Systems, and Applications, 1999. International Symposium

Page(s): 131 -134

[\[Abstract\]](#) [\[PDF Full-Text \(204 KB\)\]](#) **CNF**

[Home](#) | [Log-out](#) | [Journals](#) | [Conference Proceedings](#) | [Standards](#) | [Search by Author](#) | [Basic Search](#) | [Advanced Search](#)  
[Join IEEE](#) | [Web Account](#) | [New this week](#) | [OPAC Linking Information](#) | [Your Feedback](#) | [Technical Support](#) | [Email Alerting](#)  
[No Robots Please](#) | [Release Notes](#) | [IEEE Online Publications](#) | [Help](#) | [FAQ](#) | [Terms](#) | [Back to Top](#)

Copyright © 2002 IEEE — All rights reserved